

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	Group Art Unit: 3742
Koichiro TANAKA)	Examiner: M. Alexandra Elve
Serial No. 10/721,075)	Confirmation No.: 7829
Filed: November 26, 2003)	
For: LASER IRRADIATION APPARATUS,)	
LASER IRRADIATION METHOD,)	
AND METHOD FOR)	
MANUFACTURING A		
SEMICONDUCTOR DEVICE		

AMENDMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated February 20, 2009, please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 15 of this paper.